

Abstract:

Method for Treating Etchant

In order to ensure an easy operation, a decreased cost in maintenance and installation, and a safety and effective use of chlorine gas generated in a closed system, a new method for treating an etchant is offered. The method

5 comprises the following steps of; ① treating an etchant including copper (I) chloride or ferric chloride containing copper by means of an electrolysis using a diaphragm to withdraw copper electrolytically deposited in a cathode cell, ② supplying chlorine gas generated in an anode cell

10 into another etchant used in an etching process, thereby enabling the etchant to be regenerated.

This Sheet Has Been Replaced

